



IEEE SW Test Workshop

Semiconductor Wafer Test Workshop

June 9 - 12, 2013 | San Diego, California

Automated Probe Card Repair

Based on an Advanced Closed Loop
Manufacturing Approach

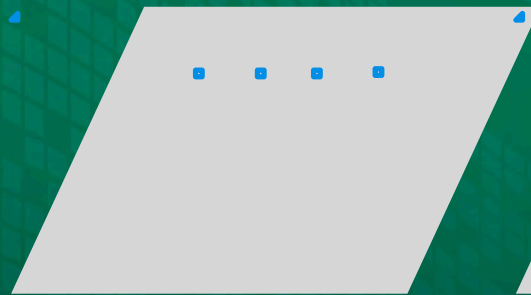


Stefan Scherer
Mark Raleigh

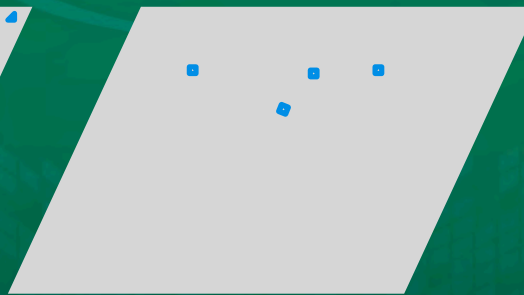
Alicona Manufacturing

Probe Card Repair Situation

- Probe card repair is a costly and demanding manual challenge



probe card with correct probes



probe card with damaged probe



The card is designed with a certain redundancy thus if the card is malfunctioning multiple probes are damaged.

Current Situation

- **Situation 1:**
Manual repair station

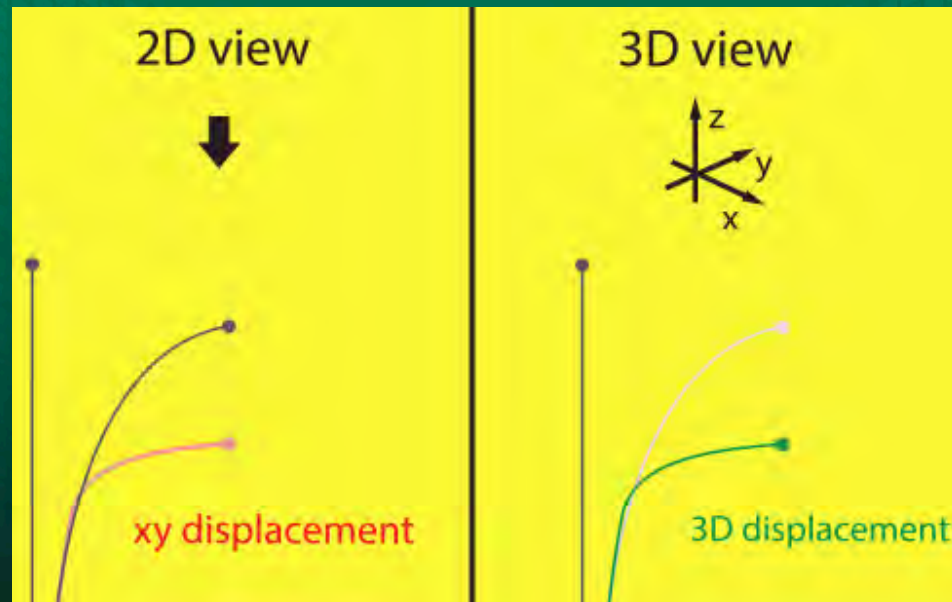


- **Situation 2:**
Manual repair station
with metrology support




Current Challenges

- Systems mostly just “support” the manual repair procedure
- Probe array is challenging to deal with
- Semi automated metrology has referencing limitations
- 2D metrology provides limited position accuracy



And in the Future?



**Reduced probe size
will increase the demand
to a level that cannot be
handled manually anymore**



Our Approach

- Fully automated system
- Based on an intelligent 3D measuring system combined with a gripping system
- Both mounted on a high precision three axis machine
- Closed loop verification of repair process
- Patent pending manipulator



Automated Probe Head Repair



Machining platform
(high precision xyz movement
plus tactile touch sensing)

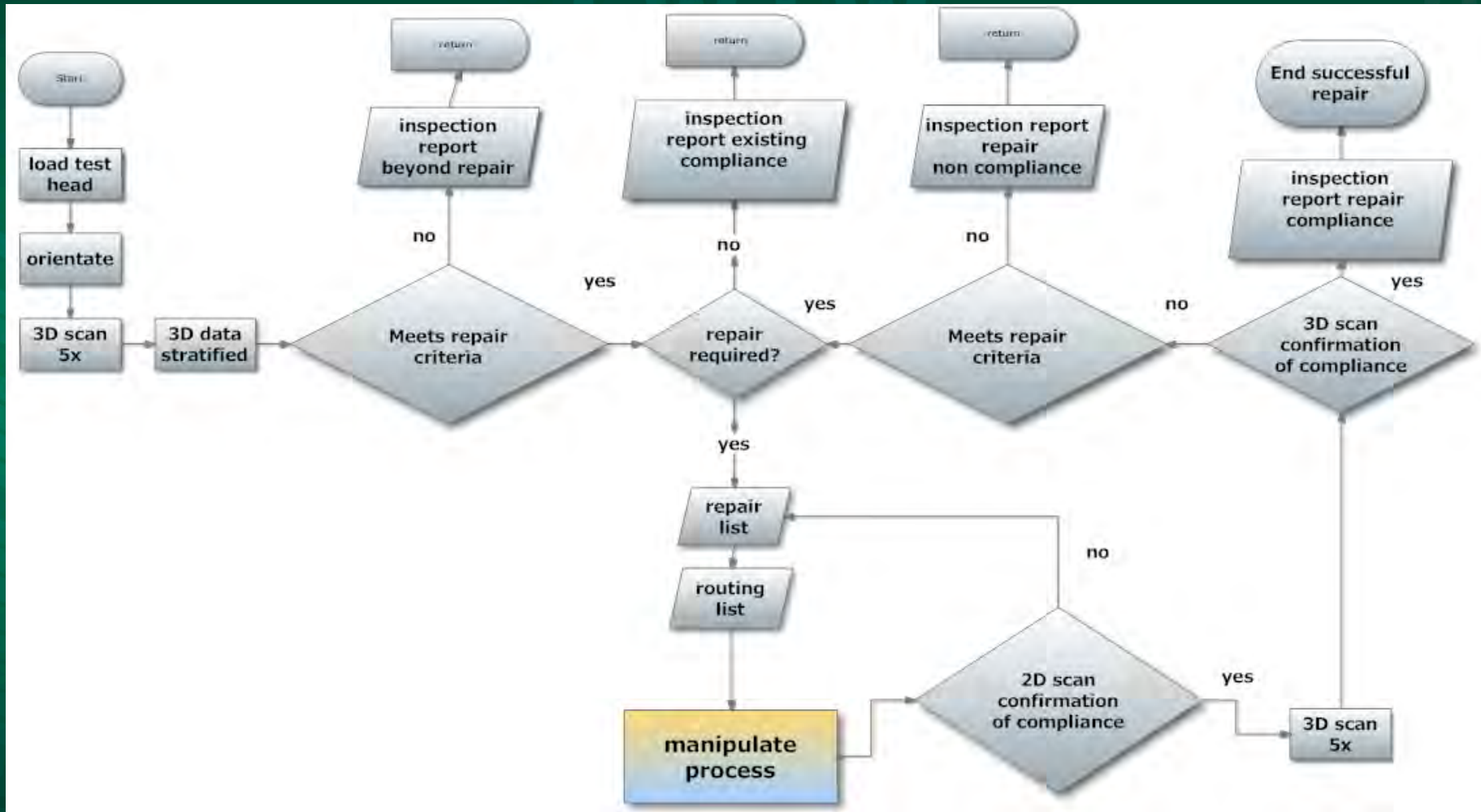


Probe manipulator for
3D probe positioning

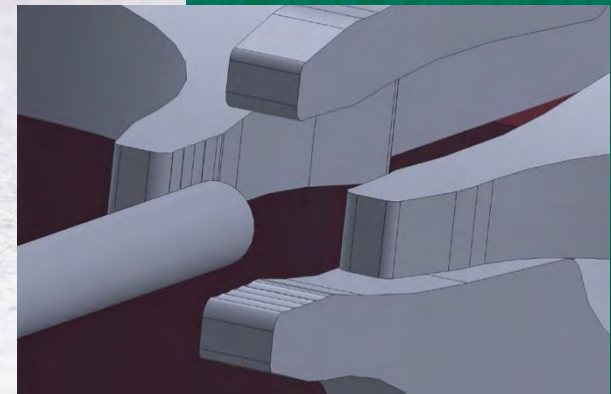
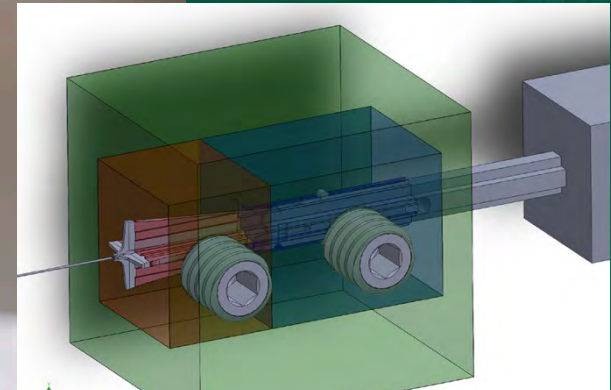
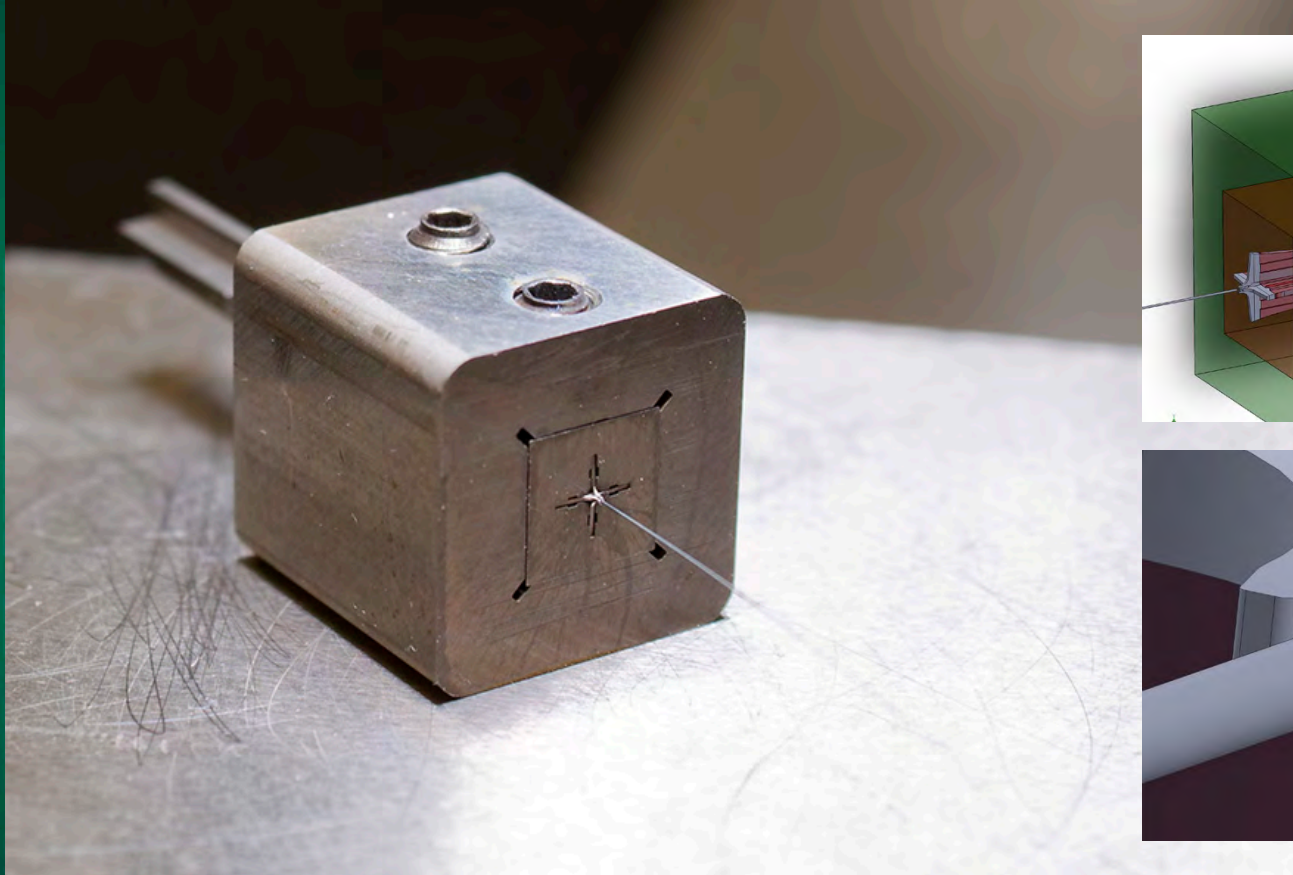


3D vision and
metrology sensor

The Process



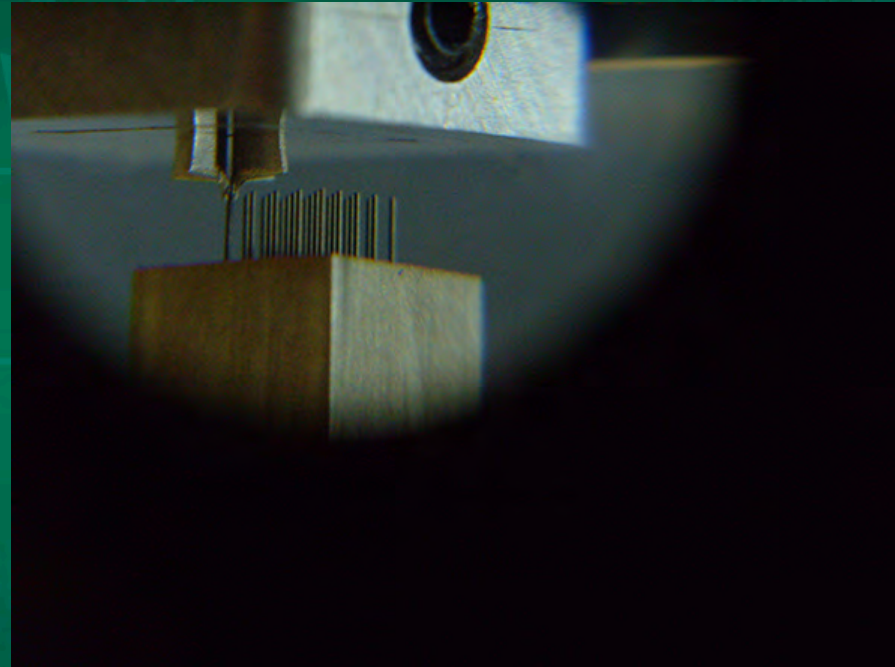
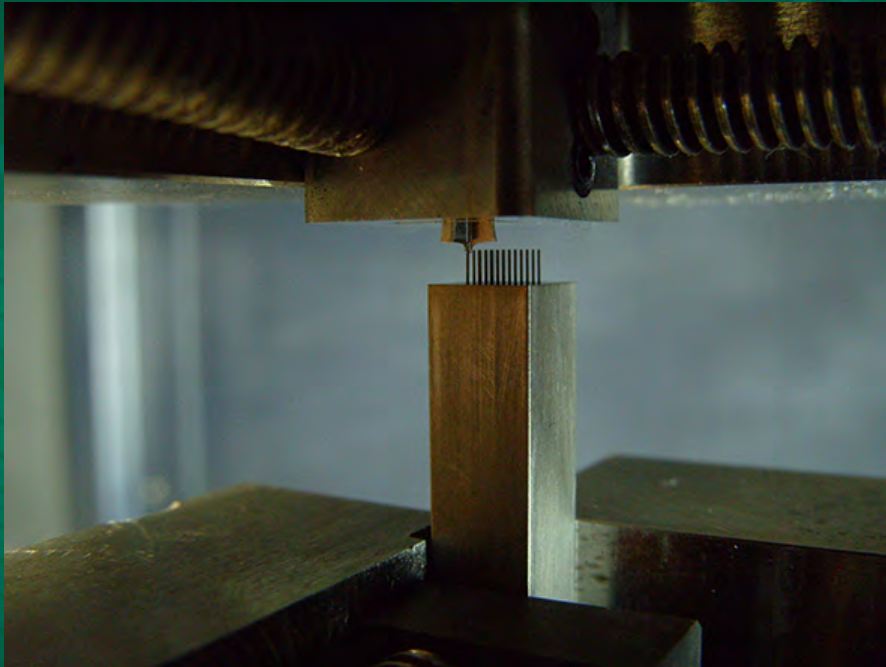
Innovative Gripping Design



75micron Gripper

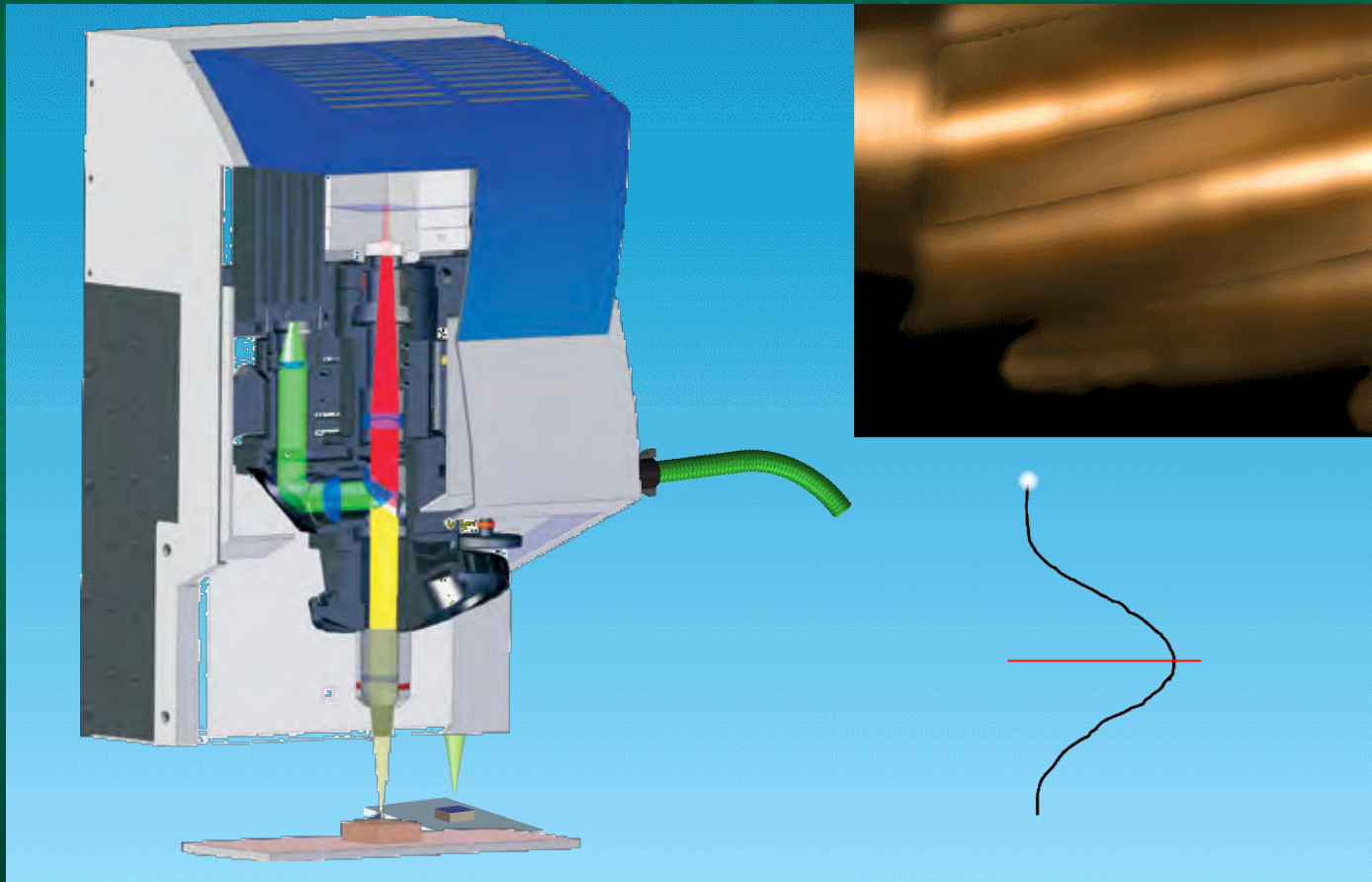


Gripper in Use



3D rather than 2D

- Our solution: Focus-Variation

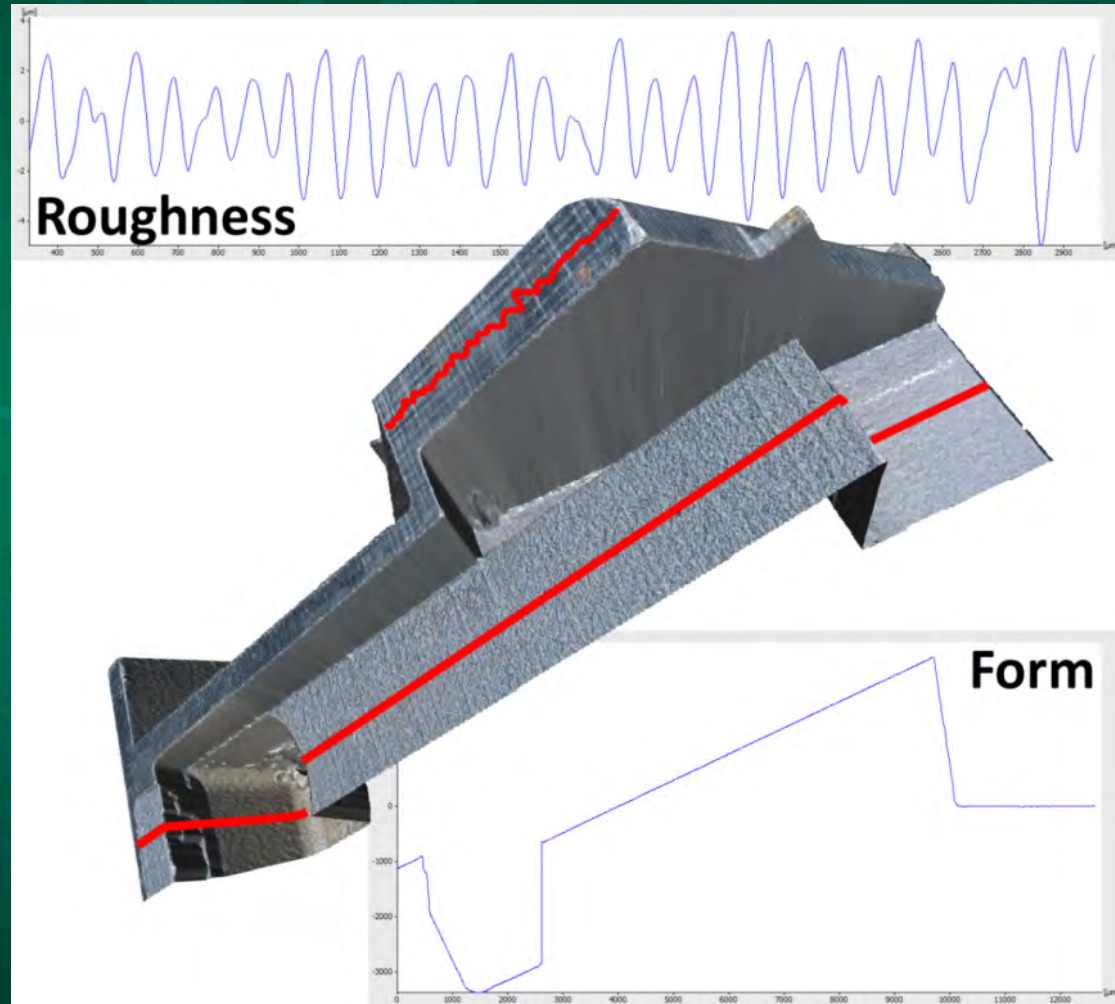
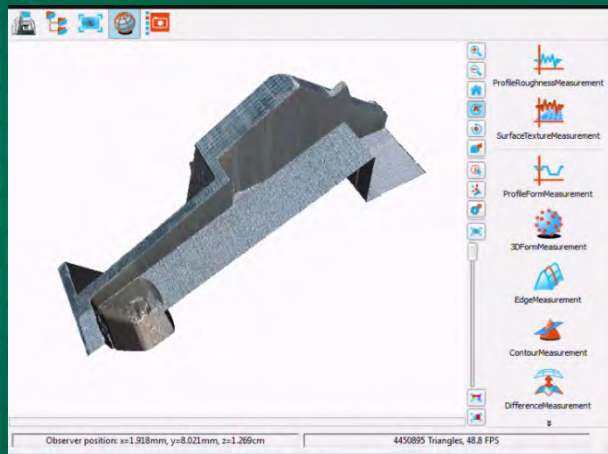


Information of a Measurement

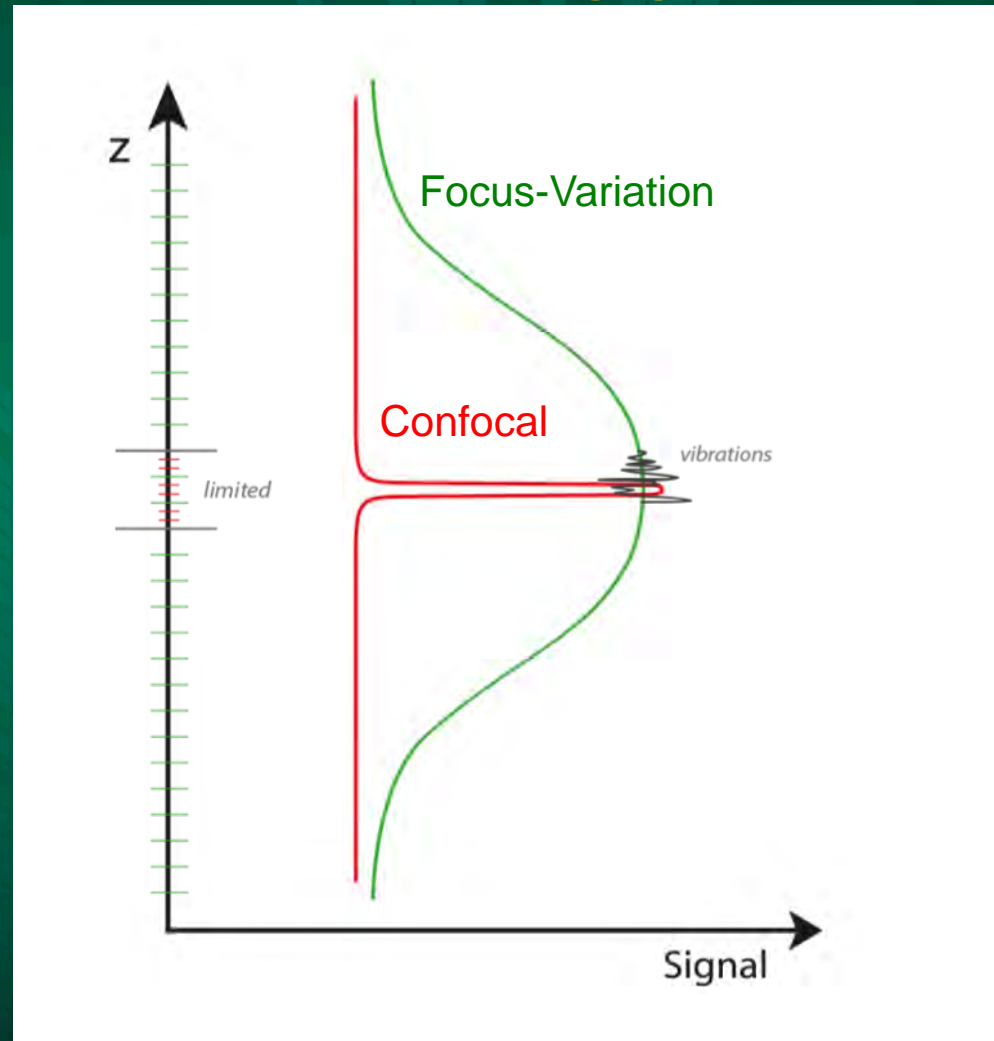
- 3D position (x, y, z)
- Repeatability
- Registered true color



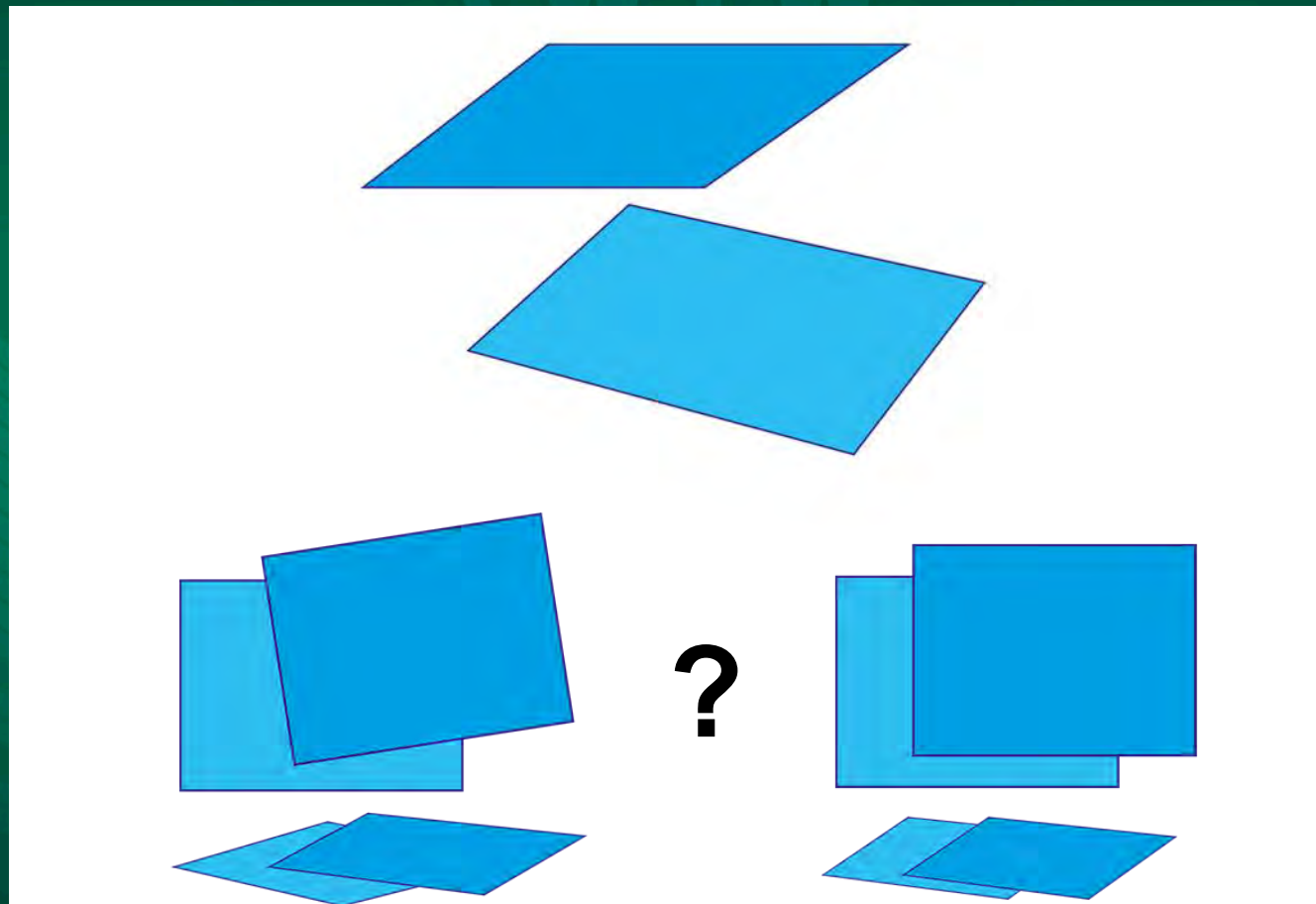
Form and Roughness with one System



Especially Robust in Industrial Applications



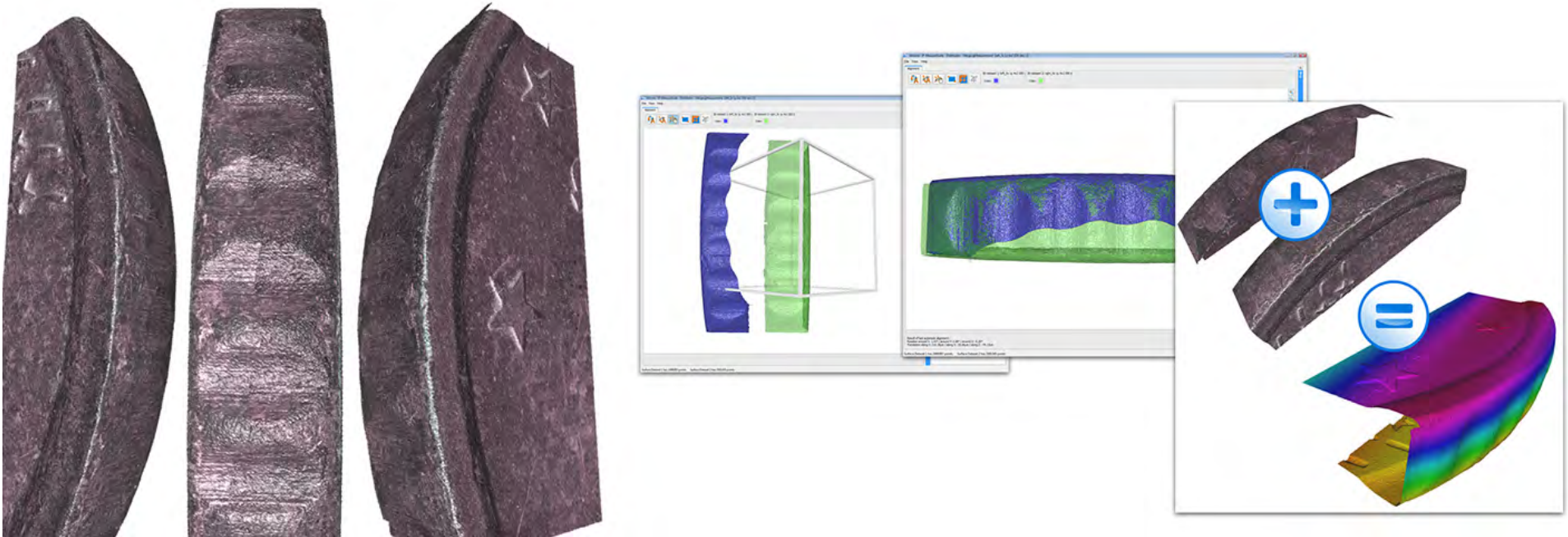
Real 3D Technology



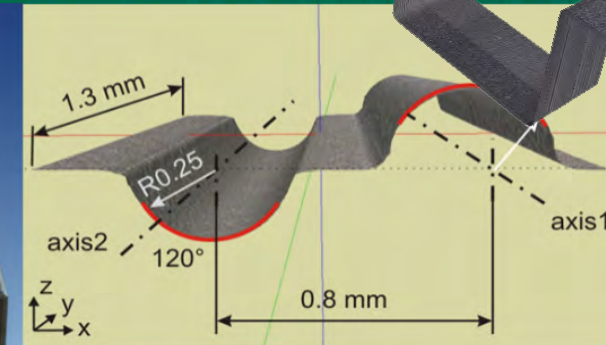
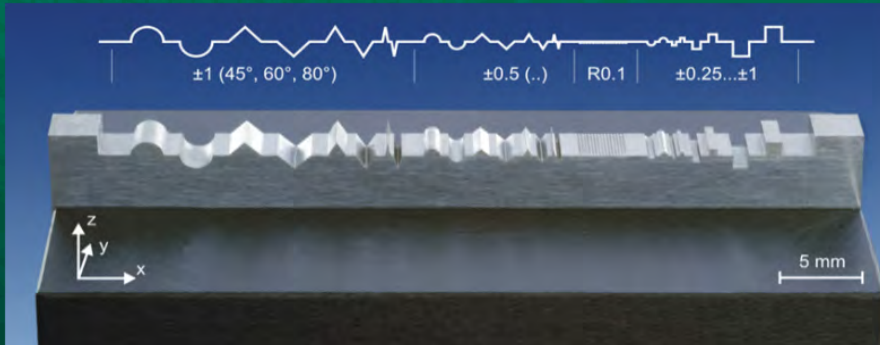
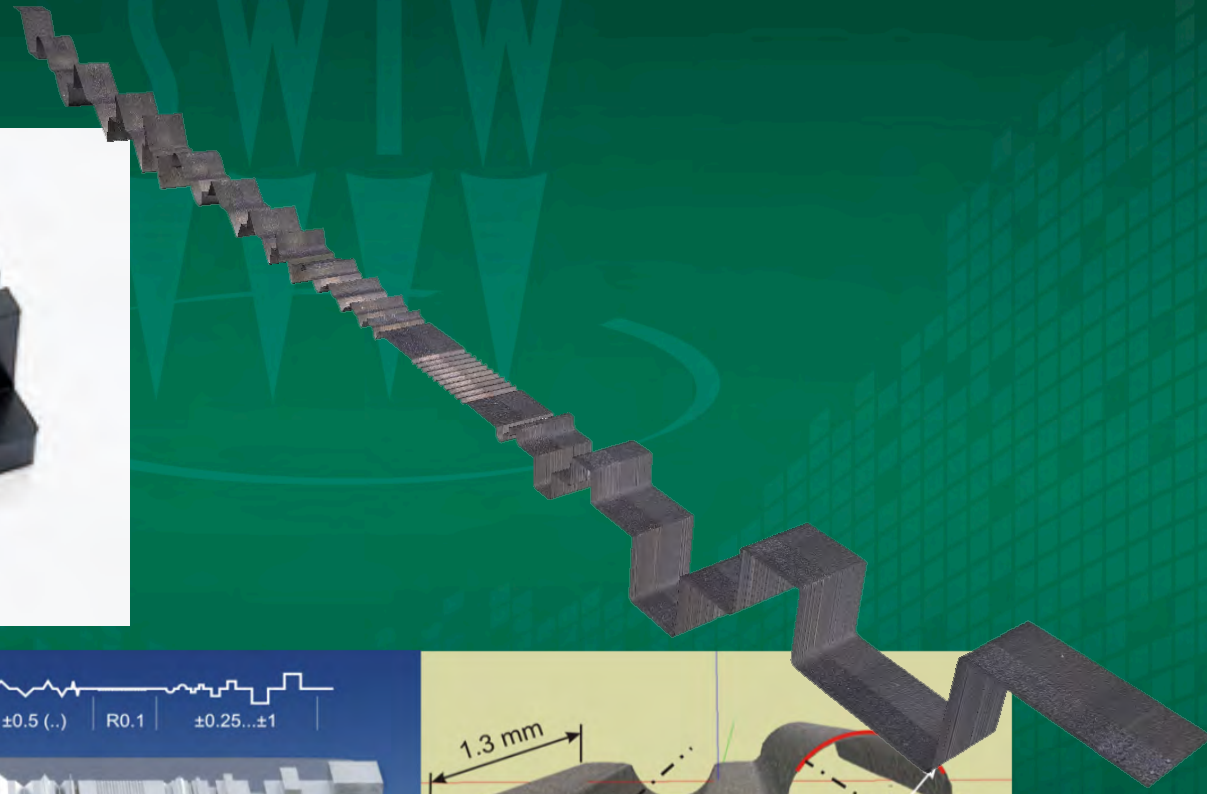


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Fusion Technology



Accuracy Proof - Form



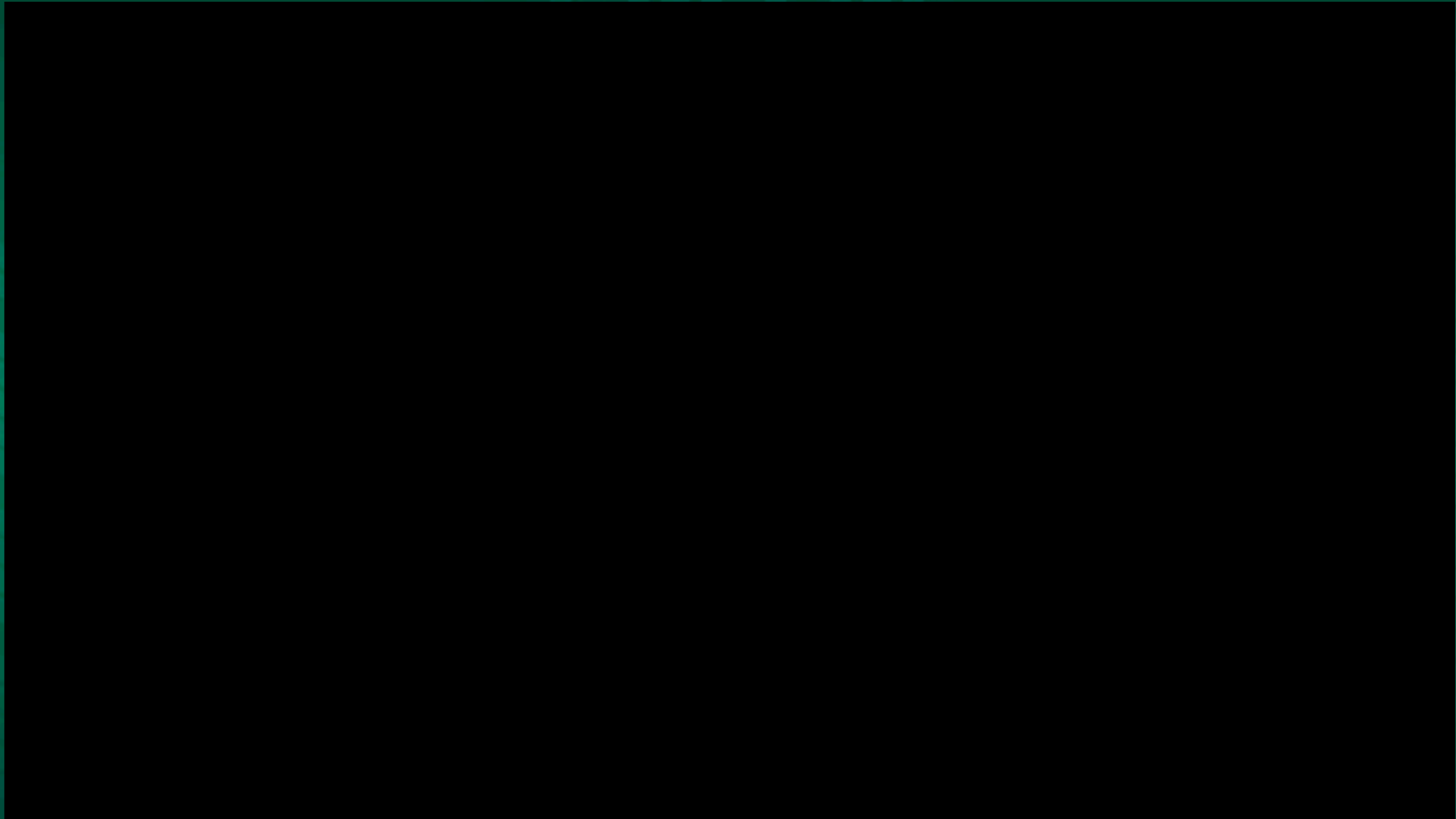
The Eye for Probe Card Repair



IF-SensorR25

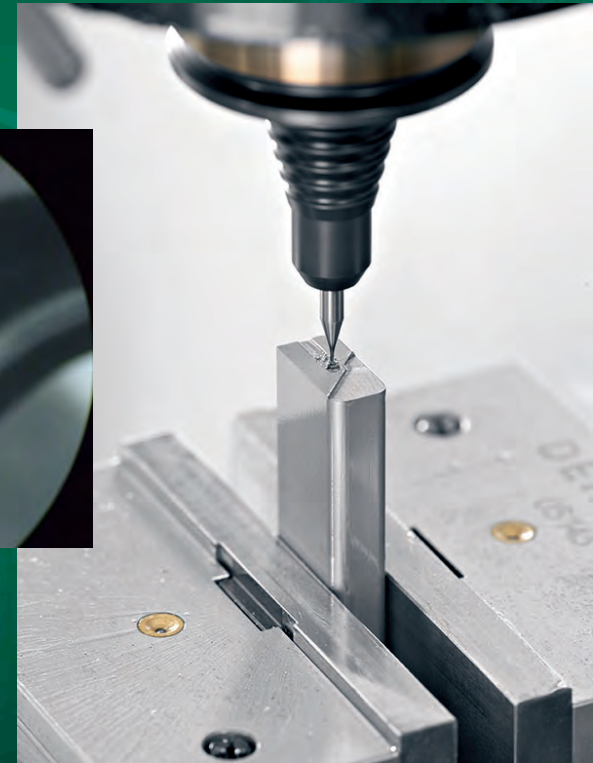
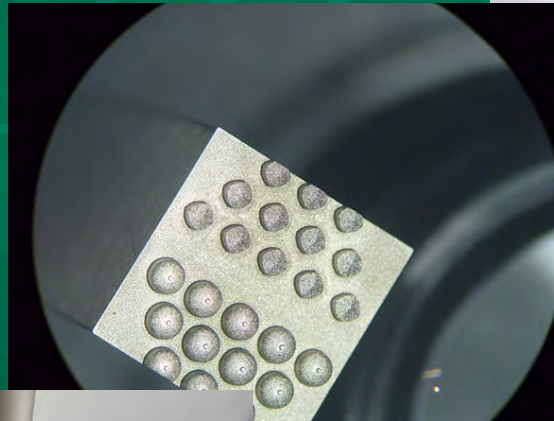
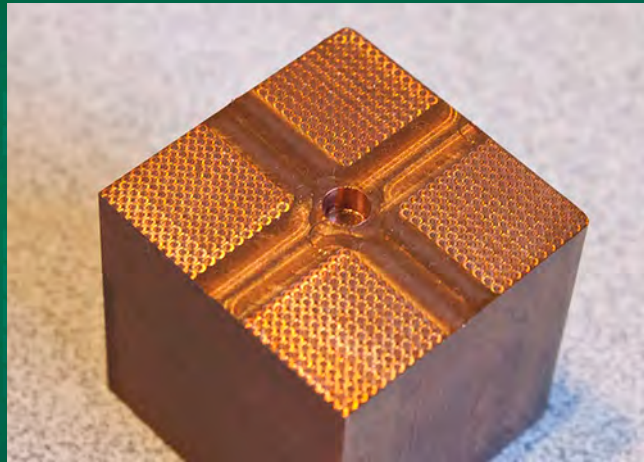
Sampling distance	μm	0.2
Min. repeatability (vertical)	nm	8
Min. measurable radius	μm	2
Min. measurable wedge angle	$^{\circ}$	20
Min. measurable roughness (Ra)	nm	80
Min. measurable roughness (Sa)	nm	50

Experimental Result



Repair station for manufacturing

- Repair station can be utilized for closed loop manufacturing of microparts





Outlook

- Serial tests are being performed
- Available as a commercial solution
- Various probe geometries have to be verified

